

ABSTRACT OF THE DISCLOSURE

In a method of manufacturing a thin-film magnetic head, a bottom pole layer is formed and a thin-film coil is formed on the bottom pole layer. A recording gap layer is then formed on the pole portion of the bottom pole layer.

- 5 Next, the recording gap layer and a portion of the bottom pole layer are selectively etched through the use of a mask so as to form an end portion of the recording gap layer for defining the throat height. Next, a nonmagnetic layer is formed to fill the etched portions of the recording gap layer and the bottom pole layer while the mask is left unremoved. Next, the mask is
- 10 removed, and the top surfaces of the recording gap layer and the nonmagnetic layer are flattened by polishing. A top pole layer is formed on the flattened top surfaces of the recording gap layer and the nonmagnetic layer.